

Appl. No. : 828,550
Filed : April 6, 2001

50. The apparatus of Claim 15, wherein said devitrification barrier coating is formed by sputtering.

51. The method of Claim 25, wherein coating at least a portion of said one or more vitreous components with a barrier layer includes using sputtering to form said barrier layer.

52. The method of Claim 27, wherein said step of forming the barrier layer out of silicon nitride includes using sputtering to form said barrier layer.

53. The support device of Claim 39, wherein said devitrification barrier coating is formed by CVD deposition.

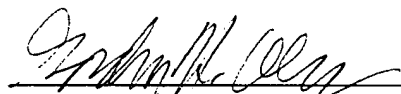
54. The support device of Claim 39, wherein said devitrification barrier coating is formed by sputtering.

Respectfully submitted,

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